

Centre For Advanced Electronics & Photovoltaic Engineering (CAEPE)											
International Islamic University Islamabad (IIUI)											
SERVICE MODEL: MACHINE EXPENDABLES AND CONSUMABLES SERVICE CONTRIBUTION (TESTING CHARGES)											
Name of Lab Incharge/Focal Person : Email ID of Lab Incharge/Focal Person: Postal Address of Lab/Center:	Engr. Shoib Alam	Position of Lab Incharge/Focal Person:		Laboratories Manager 051-9019927 CENTRE FOR ADVANCED ELECTRONICS & PHOTOVOLTAIC ENGINEERING (CAEPE) GROUND FLOOR, SHARED BLOCK INTERNATIONAL ISLAMIC UNIVERSITY, SECTOR H-10 ISLAMABAD, PAKISTAN							
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Measurement Analysis											
Electrical/Electronics/Charge Based											
S.No.	Name of Equipment	Status (Operational)	Particulars of Tests	IIU Internal Users	University Other Than IIU	Comercial Test					
1	NANO-CHIP Reliability Grade Hall Effect System	Operational	Hall effect measurement/Quick scan (At room temperature) (Mobility, Conductivity, Dopeant type, Carrier concentration, Etc)	1600/- Per Sample	2000/-	2500/-					
2	NANO-CHIP Reliability Grade Hall Effect System	Operational	Hall effect measurement/Quick scan (At low temperature 77K) (Mobility, Conductivity, Dopeant type, Carrier concentration, Etc)	2000/- Per Sample	2200/-	3500/-					
3	Multi Head Probe Station/4 point probing	Operational	Wafer or Circuit level Electrical Characterization (I-V, C-V, G-V, P-V measurements)	2800/- Per Sample	3000/-	3200/-					
4	ASMEC Electro-Physical Characterization System	Operational	Power/Energy Analysis	1500/- Per Sample	1800/-	2200/-					
5	ASMEC Electro-Physical Characterization System	Operational	Charge Analysis	1500/- Per Sample	1800/-	2200/-					
6	ASMEC Electro-Physical Characterization System	Operational	2 point probing (Arrhenius Analysis/Activation Energy) (Under vacuum) (77K-500K)	3000/- Per Hour	3500/-	4000/-					
7	ASMEC Electro-Physical Characterization System	Operational	2 point Probing (I-V Characterization) (Under vacuum) (Insitu thermal analysis 77k to 500k)	2500/- Per Hour	2800/-	3000/-					
8	ASMEC Electro-Physical Characterization System	Operational	2 point Probing (G-V characterization) (Under Vacuum) (Insitu thermal analysis 77k to 500k)	2500/- Per Hour	2800/-	3000/-					
9	ASMEC Electro-Physical Characterization System	Operational	C-V Characterization (Pulse and line scanned) (Under Vacuum) (Insitu thermal analysis 77k to 500k)	3000/- Per Hour	3200/-	3800/-					
10	ASMEC Electro-Physical Characterization System	Operational	Charge-Deep Level Transient Spectroscopy (Q-DLTS) (Under Vacuum) (Insitu thermal analysis 77k to 500k)	3500/- Per Hour	4000/-	4500/-					
11	ASMEC Electro-Physical Characterization System	Operational	Photo-stimulated Internal Field Transient Spectroscopy (PIFTS) (Under Vacuum) (Insitu thermal analysis 77k to 500k)	3000/- Per Hour	3500/-	4000/-					
12	ASMEC Electro-Physical Characterization System	Operational	I-V Characterization (Room temperature scan)	1500/- Per Sample	1800/-	2000/-					
13	ASMEC Electro-Physical Characterization System	Operational	G-V characterization (Room temperature scan)	1500/- Per Sample	1800/-	2000/-					
14	ASMEC Electro-Physical Characterization System	Operational	C-V Characterization (Room temperature scan)	1500/- Per Sample	1800/-	2000/-					
15	ASMEC Electro-Physical Characterization System	Operational	Charge-Deep Level Transient Spectroscopy (Q-DLTS) (Room temperature scan)	2000/- Per Sample	2300/-	2600/-					
16	ASMEC Electro-Physical Characterization System	Operational	Photo-stimulated Internal Field Transient Spectroscopy (PIFTS) (Room temperature scan)	1800/- Per Sample	2000/-	2200/-					
17	Hot Chuck	Operational	I-V Characterization (Non-Vacuum) (300k to 900k)	1500/- Per Hour	2000/-	2500/-					
18	Hot Chuck	Operational	G-V characterization (Non-Vacuum) (300k to 900k)	1500/- Per Hour	1800/-	2000/-					
19	Hot Chuck	Operational	C-V Characterization (Non-Vacuum) (300k to 900k)	1500/- Per Hour	2000/-	2500/-					
20	ASMEC Electro-Physical Characterization System	Operational	I(t) Transient behavior of Device w.r.t electric Current	1500/- Per Sample	1800/-	2000/-					
13	Femto-meter	Operational	Extremely low current analysis for variable application	1500/- Per Sample	1800/-	2000/-					
Process Fabrication & Deposition											
S.No.	Name of Equipment	Status (Operational)	Particulars of Tests	IIU Internal Users	University Other Than IIU	Comercial Test					
14	Atomic Layer Nano-Master Deposition System	Operational	Metal Deposition using boat and crucible (Physical Vapour Deposition)	10,500/- Per Run	13000/-	15000/-					

15	MEMS Grade Spin Coating, Baking and Stirring	Operational	Spin Deposition Coating	1200/- Per Run for Half an Hour	1500/-	1800/-
16	Electro-Chemical Impedance Spectroscopy	Operational	Impedance spectroscopy (Potentiostat/Galvanostat)	1500/- Per Sample	1800/-	2100/-
17	Fume Hood Wet Bench	Operational	Sample Cleaning	900/- Per Run for Half an hour	1300/-	1600/-
18	Hot Plate	Operational	Sample Baking/contact Sintering	800/- Per Run for Half an hour	1000/-	1500/-
19	Fume Hood Wet Bench	Operational	Sample Chemical Etching	1800/- Per Run for Half an hour	2000/-	2500/-
20	Rapid thermal Furnace	Operational	RTA/Furnace Annealing	2000/- Per Run	2500/-	3000/-
21	Rapid thermal Furnace	Operational	Rapid thermal Oxidation	2500/- Per Run	3000/-	3500/-
22	Rapid thermal Furnace	Operational	Rapid thermal Nitridation	3500/- Per Run	4000/-	4500/-
23	Magnetron Plasma Sputtering Coater	Operational	Deposition Sputtering (Magnetron) Dual Mode both DC and RF	8500/- Per Run	10,000/-	13,000/-
24	Mask Aligner	Operational	Photo-lithography (Depends upon the nature of application availability of the mask and over all experimentation)	6000/- Per Sample	8000/-	10,000/-
25	Electro Spinning & Electro Spraying	Operational	Electro Spinning & Electro Spraying of nano layers, fibers and materials for versatile applications	3500/- Per Sample	4000/-	4500/-
26	Plasma Enhanced Chemical Vapor Deposition (PECVD) System	Operational	Deposition (PECVD)	7500/- Per Run	8500/-	10,000/-

Magnetic

27	Vibrating Sample Magnetometer	Under Commissioning	Magnetic Measurements	6000/-	7000/-	8000/-
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Structural Morphology & Imaging

S.No.	Name of Equipment	Status (Operational)	Particulars of Tests	IIU Internal Users	University Other Than IIU	Comercial Test
28	Atomic Force Microscopy	Operational	Atomic Scale Microscopy measurements AFM and STM Mode	4800/- Per Sample	5500/-	7000/-
29	Scanning Electron Microscopy	Operational	Scanning Electron Microscopy (BSE, EDX and Imaging down to Sub-micron level)	6000/- Per Sample	7500/-	9000/-
30	X-Ray Diffraction System	Operational	Diffracton scan (Indices, planes, Material composition analysis)	4000/- Per Sample	5000/-	6000/-
31	High Resolution Thickness Profiling	Operational	Thickness Profiling of the surface down to nm through stylus scanning	2500/- Per Sample	3000/-	3500/-

Optical

32	Spectroscopic Ellipsometer	Operational	Spectroscopic Ellipsometry (Full Scan SE) (Refractive index, Extinction coefficient, dielectric Coefficient, Thickness of the layer)	3500/- Per Sample	4000/-	5000/-
33	Photoluminescence System (PLS)	Operational	Photoluminescence System (PLS) (Optical bandgap, defects mapping) Low temperature analysis	3000/- Per Sample	4000/-	5000/-

Solar Cell/PV Evaluation

S.No.	Name of Equipment	Status (Operational)	Particulars of Tests	IIU Internal Users	University Other Than IIU	Comercial Test
34	Sun Simulator Class AAA	Operational	Sun Simulator test, Efficency of the cells along with the packing fraction, electrical analysis, etc	2000/- Per Sample	2500/-	3500/-